

Notice of References Cited

Application/Control No.

10/587,546

Applicant(s)/Patent Under
Reexamination
BAI ET AL.

Examiner

DANIEL C. MCCracken

Art Unit

1736

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
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FOREIGN PATENT DOCUMENTS

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	Q					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Choi, et al., Controlled deposition of carbon nanotubes on a patterned substrate, Surface Science 2000; 462: 195-202			
	V	Xu, et al., A method for fabricating large-area, patterned, carbon nanotube field emitters, Applied Physics Letters 1999; 74(17): 2549-2551			
	W				
	X				

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.